

Characterization of binary, ternary and quaternary hard coatings in the material system V-Al-C-N produced by industrial scale reactive magnetron sputter deposition

S. Kolozsvári¹, P. Pesch¹, C. Ziebert², M. Stueber, S. Ulrich²

¹*TZO – Technologiezentrum für Oberflächentechnik Rheinbreitbach GmbH, Maarweg 30, 53619 Rheinbreitbach, Germany*

²*Forschungszentrum Karlsruhe, Institut für Materialforschung I, Hermann-von-Helmholtz-Platz 1, 76344 Eggenstein-Leopoldshafen, Germany*

Binary, ternary and quaternary hard coatings in the system V-Al-C-N (VN, AlN, VC, VAIN and VAICN) were deposited by industrial-size/industrial scale reactive d.c. and r.f.-magnetron sputtering in an Ar/N and an Ar/CH₄ plasma from a V target and/or Al target, respectively from an VAl₂₀-target (V target with 20 Al-plugs). For each experiment, Si (100) substrates and polished 1.2379 steel substrates were placed on the rotating substrate table with variable rotation speed and rotation axes. VN coatings were deposited at a constant Ar gas flow of 250mln, while the bias voltage applied to the substrate table was systematically varied between -80 and -200V. VC coatings were deposited at constant Ar:CH₄ gas flow ratio (250:60) and systematically varied bias voltage between -80 and -200V and respectively at constant bias voltage from -170V and varied Ar:CH₄ ratio through changing the CH₄ amount in the plasma. For the deposition of AlN, VAIN and VAICN coatings the bias voltage, the Ar:N ratio and the total gas pressure were varied. The chemical composition of the obtained coatings was determined by electron microprobe analysis and the crystal structure of the films was characterized by X-ray diffraction. The influence of the process parameter variation on the mechanical properties hardness, reduced elastic modulus and critical load of failure have been studied by microindentation and scratch test. The surface roughness of the as-deposited samples was examined as a function of the initial substrate surface roughness. It was possible to achieve a large variation in the hardness in the range from 700HV_{0.005} to 3100HV_{0.005} and in the coefficient of friction in the range from 0.2 to 0.7. Finally, the specific conditions for the formation of large-area VN, AlN, VC, VAIN and VAICN nanoscale coatings in industrial-size coating facilities are described in terms of process engineering.